



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Si Yi Li et al.

Group Art Unit: 1763

Application No.: 09/820,695

Examiner: ALLAN W OLSEN

Filing Date: March 30, 2001

Confirmation No.: 4162

Title: METHOD OF PLASMA ETCHING LOW-K DIELECTRIC MATERIALS

PETITION FOR EXTENSION OF TIME

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following extension of time is requested to: extend the time for responding to the Final Official Action dated February 27, 2004

a second month to July 27, 2004 ☐ \$155.00 ☒ \$310.00

A ☒ one ☐ two ☐ three ☐ four month Petition for Extension of Time was previously filed with the appropriate fee on June 28, 2004.

☐ An extension fee in the amount of \_\_\_\_\_ is enclosed.

☐ The shortened statutory period has been reset by an Advisory Action dated \_\_\_\_\_.

☒ Charge \$ 310.00 to Deposit Account No. 02-4800.

☐ Charge \_\_\_\_\_ to credit card. Form PTO-2038 is attached.

The Director is hereby authorized to charge any appropriate fees under 37 C.F.R. §§1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 02-4800. This paper is submitted in duplicate.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

P.O. Box 1404  
Alexandria, Virginia 22313-1404  
(703) 836-6620

By

Peter K. Skiff

Registration No. 31,917

Date: July 21, 2004

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